

Notice of References Cited	Application/Control No. 10/632,825	Applicant(s)/Patent Under Reexamination LEE ET AL.	
	Examiner Evan Pert	Art Unit 2826	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,753,618	06-2004	Basceri et al.	257/296
	B	US-2003/0232511	12-2003	Metzner et al.	438/785
	C	US-			
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	E	US-			
	F	US-			
	G	US-			
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	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Document entitled "Technology Background: Atomic Layer Deposition" from "IC Knowledge LLC" downloaded from http://www.icknowledge.com/misc_technology/Atomic%20Layer%20Deposition%20Briefing.pdf , 7 pages, 2004.
	V	
	W	
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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